

Title (en)

FLUID NOZZLE SYSTEM , ENERGY EMISSION SYSTEM FOR PHOTOLITHOGRAPHY AND ITS METHOD OF MANUFACTURE

Title (de)

FLUID-DÜSENSYSTEM, ENERGIE-EMISSIONSSYSTEM FÜR PHOTOLITHOGRAPHIE UND VERFAHREN ZUR HERSTELLUNG

Title (fr)

AJUTAGE DE LIQUIDE, SYSTEME D'EMISSION D'ENERGIE POUR PHOTOLITHOGRAPHIE ET SON PROCEDE DE FABRICATION

Publication

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Application

EP 99916360 A 19990402

Priority

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Abstract (en)

[origin: WO9951356A1] An emitted energy system for use in photolithography may include a fluid nozzle. A nozzle and its method of manufacture are provided. A nozzle (22) may include a nozzle cavity (110) disposed within a nozzle body (100) between an up-stream end (102) and a down-stream end (104). A nozzle passage (118) may be defined within the nozzle cavity (110) and extend a longitudinal length (120) from the down-stream end (104) of the nozzle body (100) into the nozzle cavity (110). A discharge orifice (124) may also be defined at the down-stream end (104) of the nozzle cavity (110) and have an associated width (126). The width (126) of the discharge orifice (124) may be substantially less than the longitudinal length (120) of the nozzle passage (118). The method of manufacture may include fabricating a recess (206) in a first side (202) of an article (200). An article passage (216) may be fabricated between a second side (204) of the article (200) and the recess (206). An insert (220) may be provided sized to fit the recess (206). An insert passage (230) may be fabricated in the insert (220). The insert (220) may then be secured in the recess (206), with the insert passage (230) and the article passage (216) aligned.

IPC 1-7

B05B 1/34; **H05G 2/00**

IPC 8 full level

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